

Plasma Electromagnetics using Dielectric Barrier Discharges

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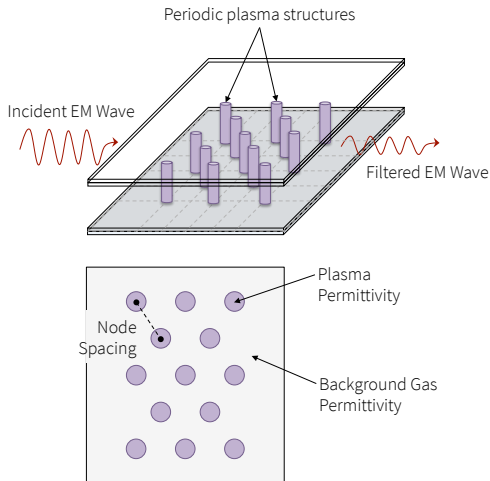
Compiled October 16, 2014

- ❖ Can control permittivity and refractive index of plasma by changing experimental conditions
- ❖ Plasma has no moving parts and high frequency response
- ❖ Adaptive optics for wavefront corrections
 - ❖ High-speed adaptive optics critical to aero-optic applications
 - ❖ Controllable plasma index of refraction
- ❖ Plasma photonic crystals for adaptive filtering
 - ❖ Controllable periodic plasma structures
 - ❖ High-speed adaptive filtering for GHz-THz
 - ❖ Aircraft radar stealth



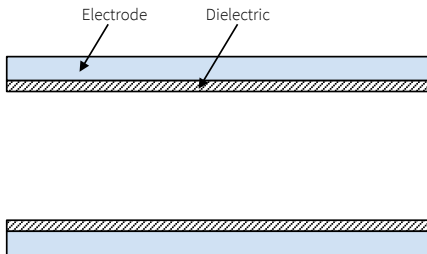
High-speed controllability of plasma makes it attractive for stealth and aero-optics.

- Experimentally generate periodic plasma structures
- Spatially periodic dielectric
- Demonstrate dynamic control spacing of plasma structures
- Determine electron density of plasma columns
- Show that plasma photonic crystal can act as an adaptive filter for a range of probing frequencies



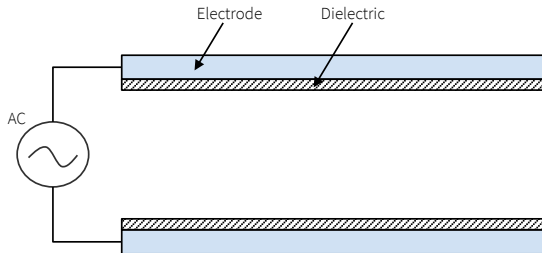
Current focus is to generate periodic plasma structures and show control over spacing.

Dielectric Barrier Discharge (DBD)



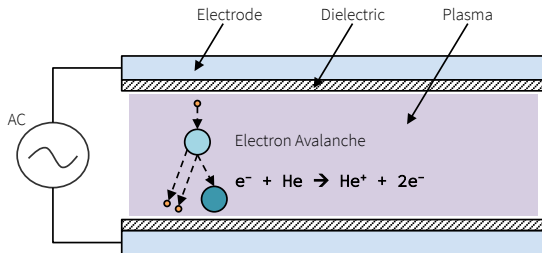
- Two electrodes separated by dielectric material

Dielectric Barrier Discharge (DBD)



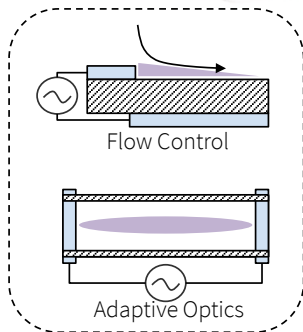
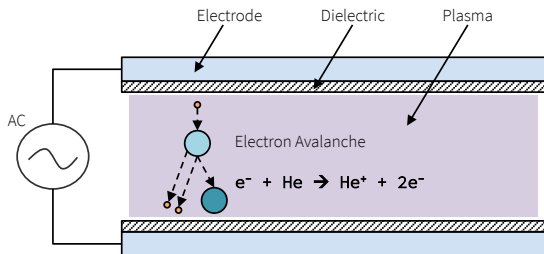
- Two electrodes separated by dielectric material
- Apply ac carrier signal (kV, kHz)

Dielectric Barrier Discharge (DBD)



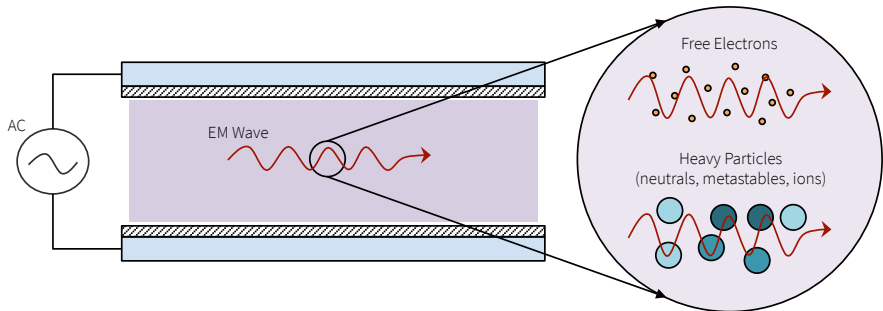
- ❖ Two electrodes separated by dielectric material
- ❖ Apply ac carrier signal (kV, kHz)
- ❖ Electric field generates electron avalanche, partially ionizes gas

Dielectric Barrier Discharge (DBD)



- ❑ Two electrodes separated by dielectric material
- ❑ Apply ac carrier signal (kV, kHz)
- ❑ Electric field generates electron avalanche, partially ionizes gas
- ❑ DBD allows for highly adaptable geometries

Investigate DBD geometries for electromagnetic control of optics and microwaves.

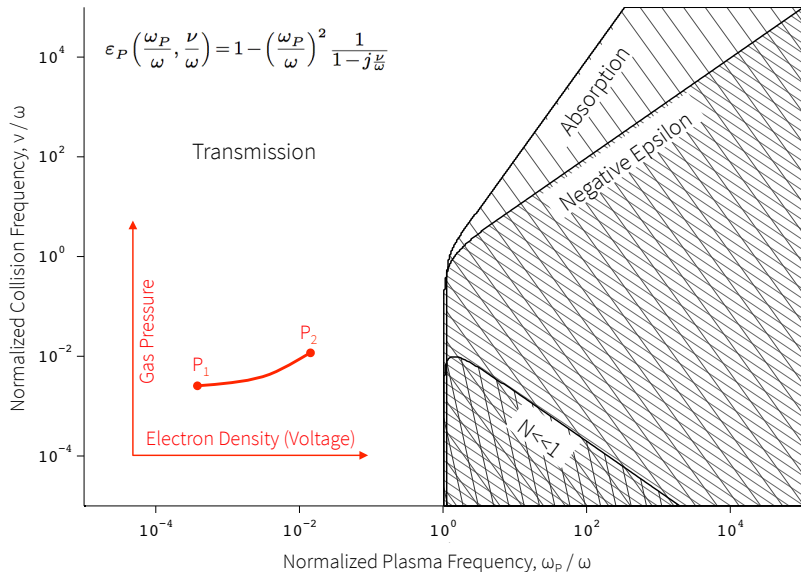


(Plasma permittivity)
$$\epsilon_P \left(\frac{\omega_P}{\omega}, \frac{\nu}{\omega} \right) = 1 - \left(\frac{\omega_P}{\omega} \right)^2 \frac{1}{1 - j \frac{\nu}{\omega}}$$

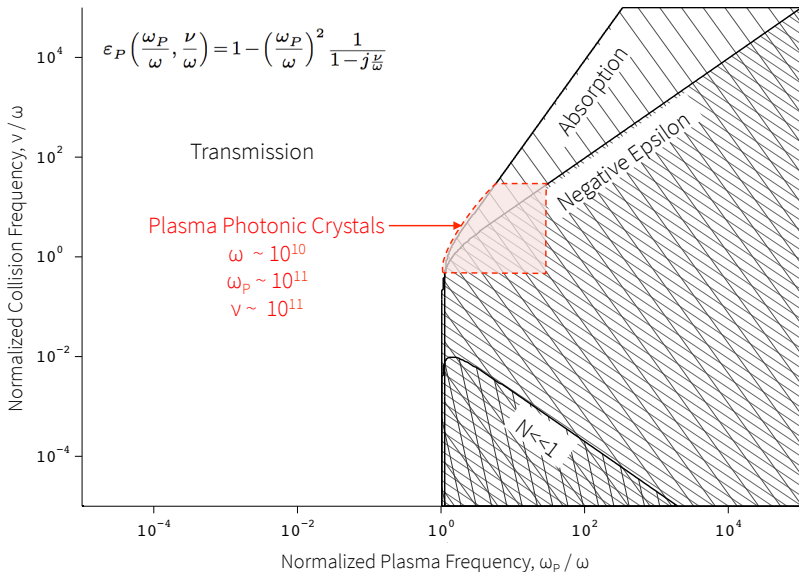
- Plasma frequency ω_P is a function of electron density, controllable by applied voltage
- Electron-neutral collision frequency ν is a function of gas pressure

Use voltage and gas pressure to control permittivity of plasma.

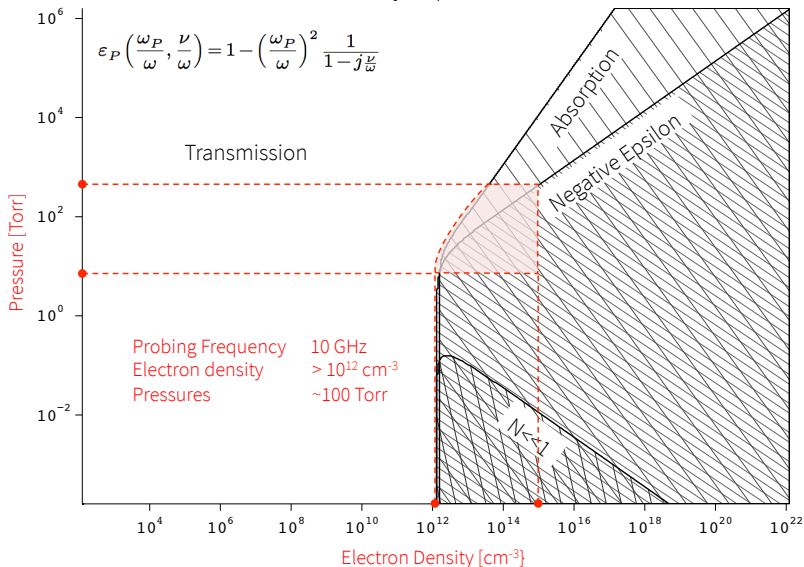
Plasma Permittivity Map



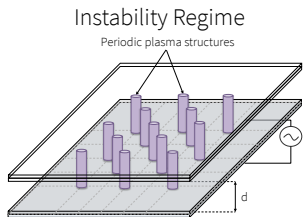
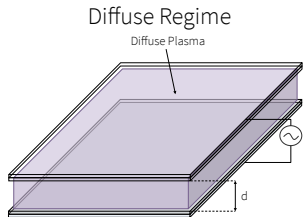
Plasma Permittivity Map



Plasma Permittivity Map for 10 GHz Radiation

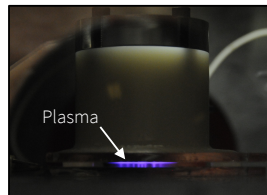
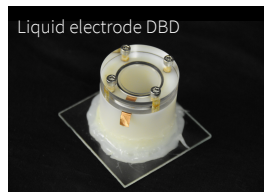
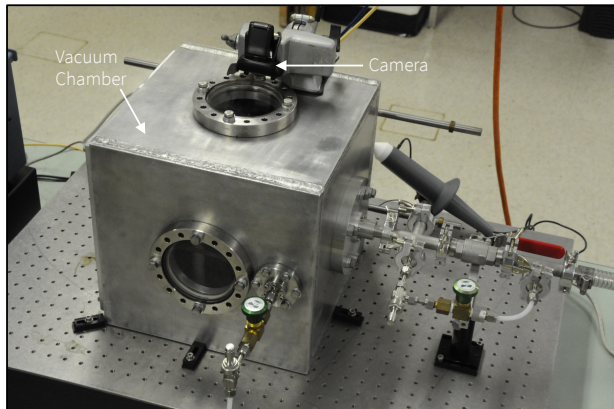


- Parallel plate electrodes and dielectrics
- Plasma regime dependent on
 - Gas pressure
 - Gap distance
 - Carrier voltage and frequency
- Plasma charge instability produces stationary, naturally spaced plasma structures
- Applied voltage changes natural spacing
- Adaptive plasma photonic crystal
- Requires sufficient electron density for absorption



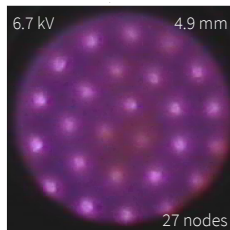
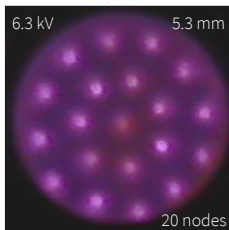
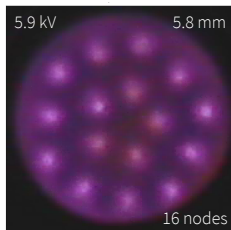
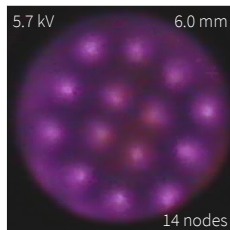
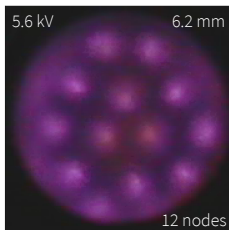
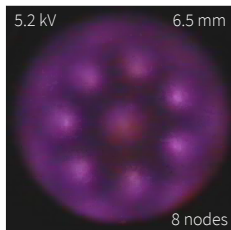
Plasma produces structures of periodic permittivity with adaptable spacing.

Experimental Setup



Use liquid electrode DBD geometry to generate plasma within a vacuum chamber.

Voltage Effect on Plasma Structures



Increasing voltage decreases the spacing between plasma nodes.

Image processing determines:

1. Node location
2. Plasma radius
3. Node spacing

Identify bad nodes and edges

Limited pixel resolution, can improve imaging system

141007_153120_068 – Nodes=20, Spacing=35.59 px, Radius=5.42 px

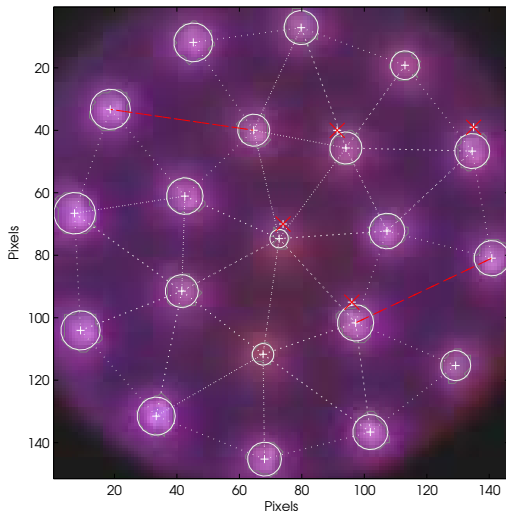
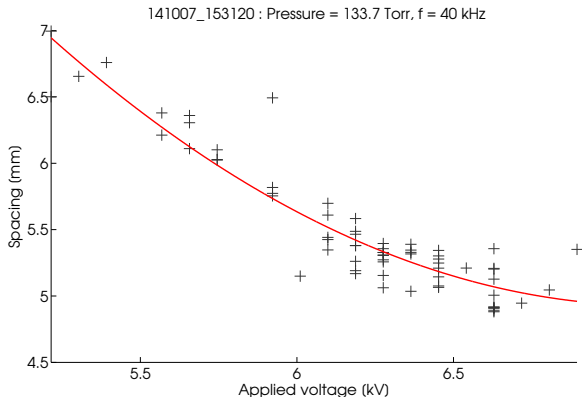


Image processing determines average plasma structure spacing at each voltage.

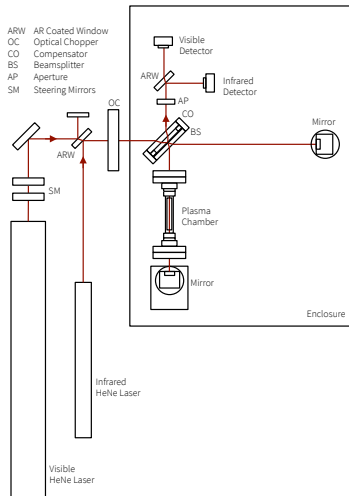


- ❑ Preliminary results show clear trend between voltage and spacing
- ❑ Is electron density sufficient for absorption?

Results demonstrate experimental control of plasma periodic spacing.

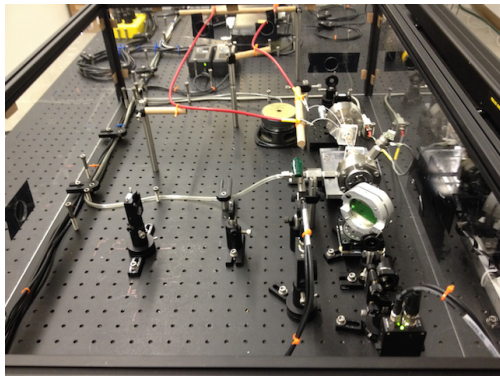
Measuring Plasma Electron Density

- Previously measured electron density for different DBD geometry
- Michelson interferometer, helium neon lasers at 633nm and 3.39 μm
- Dual wavelengths isolate effects of electron density and gas heating
- Plasma placed in one arm of interferometer
- Interference indicates phase difference between both arms

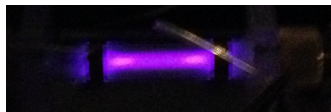
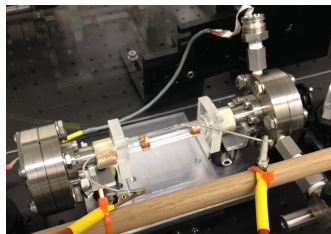


Dual wavelength interferometer provides non-invasive simultaneous measurement of plasma and heavy densities.

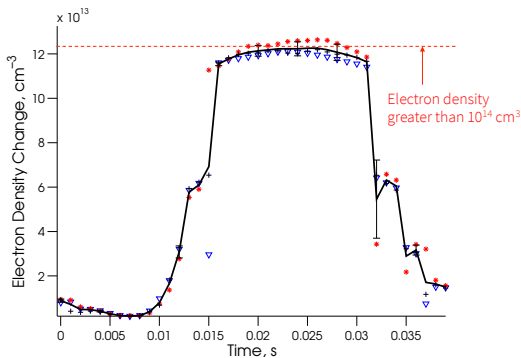
Dual Wavelength Interferometer



Cylindrical DBD



Experiment measured electron density of a cylindrical DBD geometry.



- Electron density 10^{14} cm^{-3} sufficient for absorption up to 100 GHz
- Different geometry but suggests feasibility for plasma photonic crystal DBD geometry

DBD electron density sufficient for absorption at 100 GHz.

- ❖ Seek to develop adaptive plasma photonic crystal
- ❖ Vacuum chamber experiments demonstrate adjustable plasma spacing
- ❖ Electron density measurements show that the plasma will likely be an absorbing medium
- ❖ Further investigate effects of voltage, pressure, frequency, gas
- ❖ Use data in FDTD simulations to investigate electromagnetic response
- ❖ Probe the plasma with spectrum analyzer to directly measure electromagnetic response

Questions and Comments?

Appendix

Determining the Absorbing Boundary

- Plasma complex susceptibility

$$1 + \chi = \epsilon_P = 1 - \left(\frac{\omega_P}{\omega} \right)^2 \frac{1}{1 - j \frac{\nu}{\omega}}$$

- Index of refraction and absorption coefficient

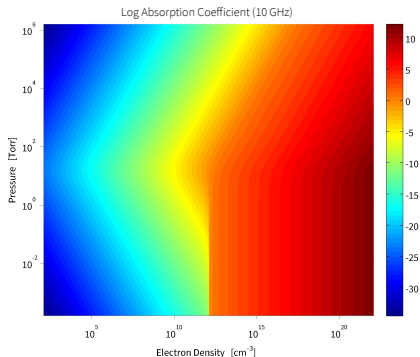
$$\beta - j \frac{1}{2} \alpha = k_0 (1 + \chi)^{1/2} = \frac{\omega}{c_0} \sqrt{\epsilon_P}$$

- Plasma absorption coefficient

$$\alpha = -2 \frac{\omega}{c_0} \Im(\sqrt{\epsilon_P})$$

- Wave is attenuated by $|\exp(-jkz)|^2 = \exp(-\alpha z)$

- Use $\alpha \geq 1$ threshold value to create boundary



- The measured plasma induced phase shift represented with

$$\Delta\phi = \frac{4\pi L}{\lambda} \left(\frac{-q^2\lambda^2 \Delta n_e}{8\pi^2\epsilon_0 c^2 m} + \left(A + \frac{B}{\lambda^2} \right) \frac{\Delta n_h}{n_{h0}} \right)$$

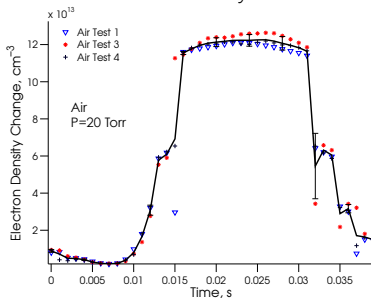
- Form linear system of equations

$$\underbrace{\frac{1}{4\pi L} \begin{bmatrix} \Delta\phi_{\lambda_1,j} \\ \Delta\phi_{\lambda_2,j} \end{bmatrix}}_{\text{Measurements}} = \underbrace{\begin{bmatrix} \frac{-q^2\lambda_1}{8\pi^2 c^2 \epsilon_0 m} & \frac{A}{n_{h0}\lambda_1} + \frac{B}{n_{h0}\lambda_1^3} \\ \frac{-q^2\lambda_2}{8\pi^2 c^2 \epsilon_0 m} & \frac{A}{n_{h0}\lambda_2} + \frac{B}{n_{h0}\lambda_2^3} \end{bmatrix}}_{\text{Constants}} \underbrace{\begin{bmatrix} \Delta n_{e,j} \\ \Delta n_{h,j} \end{bmatrix}}_{\text{Unknowns}}$$

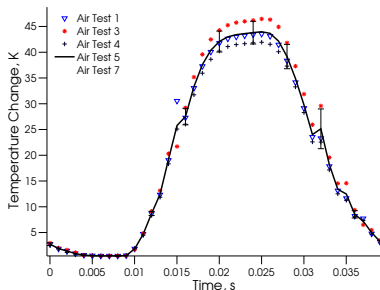
- Determine Δn_e and Δn_h using constrained least-squares solver

Phase measurements at each wavelength are used to set up a system of equations to solve for the electron and heavy particle densities.

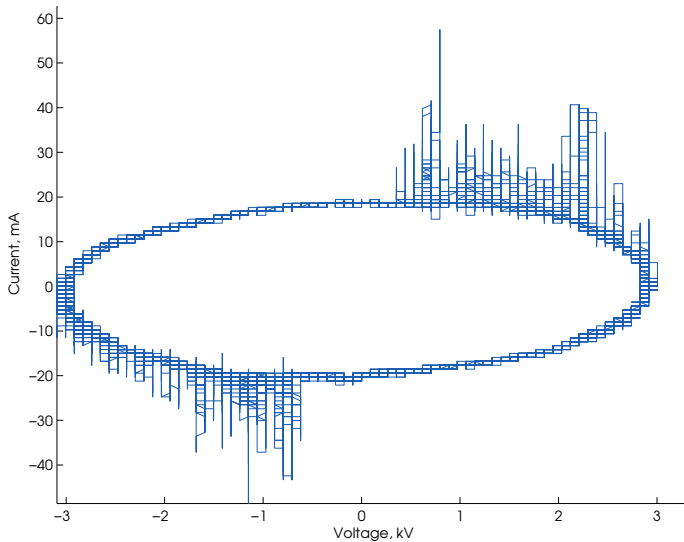
Electron Density Profile

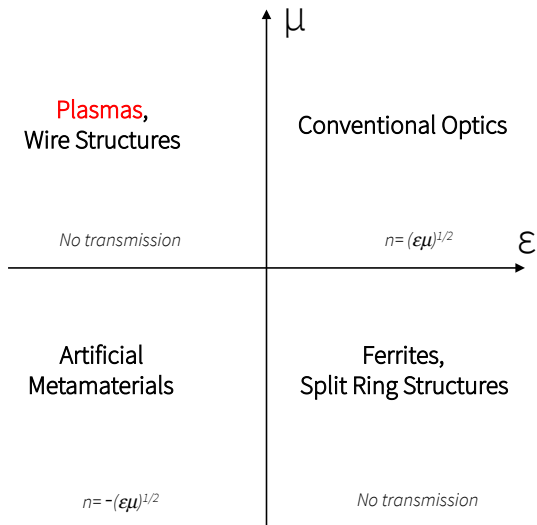


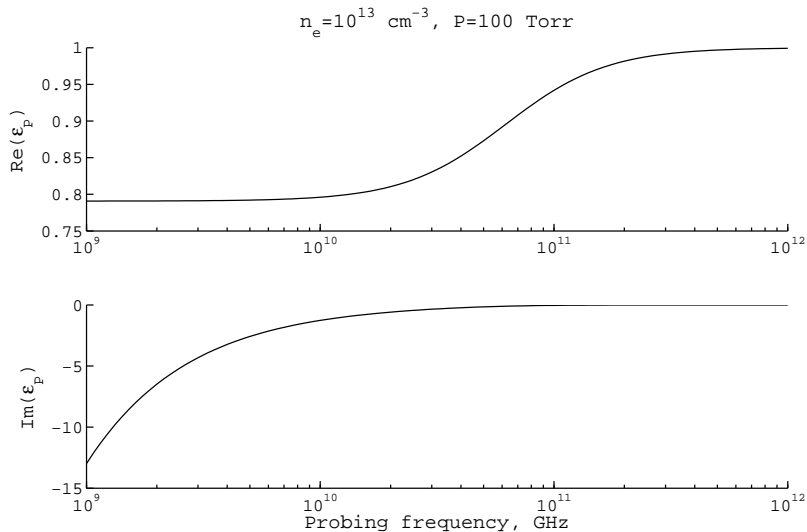
Temperature Profile

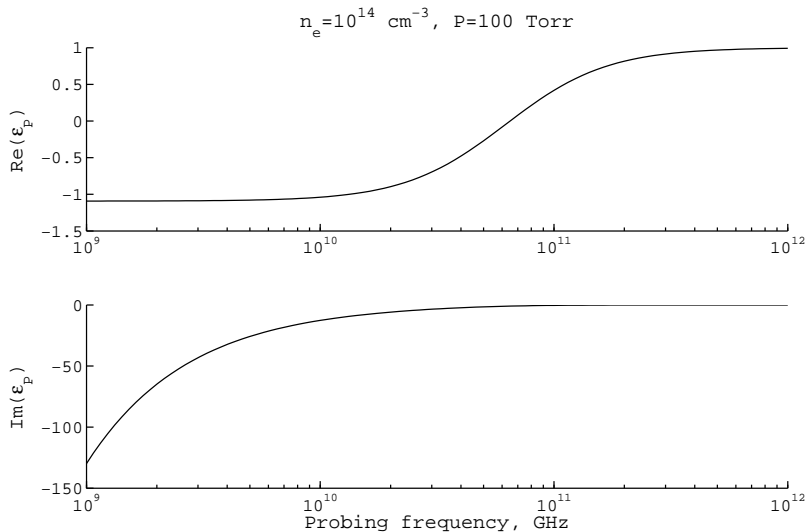


141007_153120_065 - Vpkpk=6.099 kV, Irms=14.347 mA, P=3.799 W

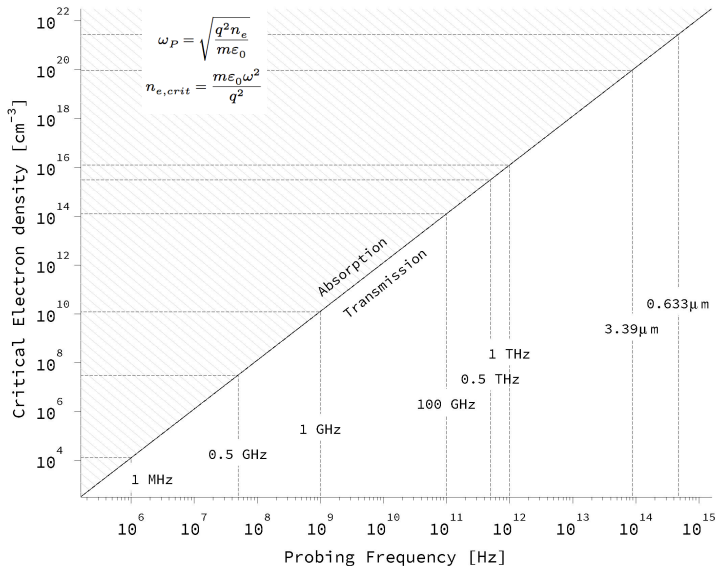




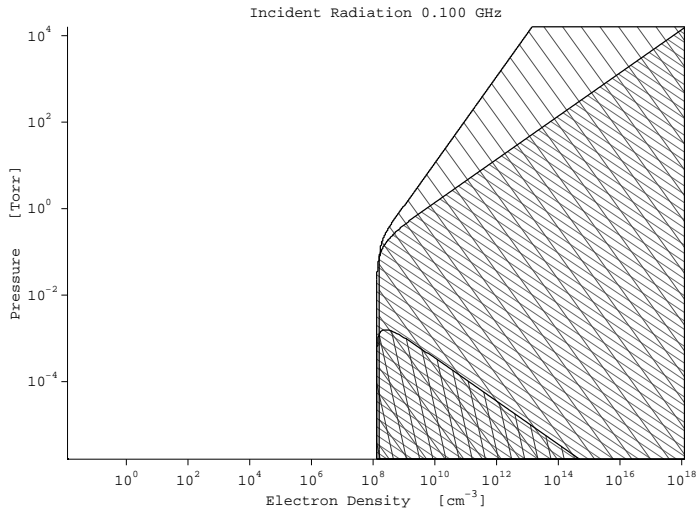




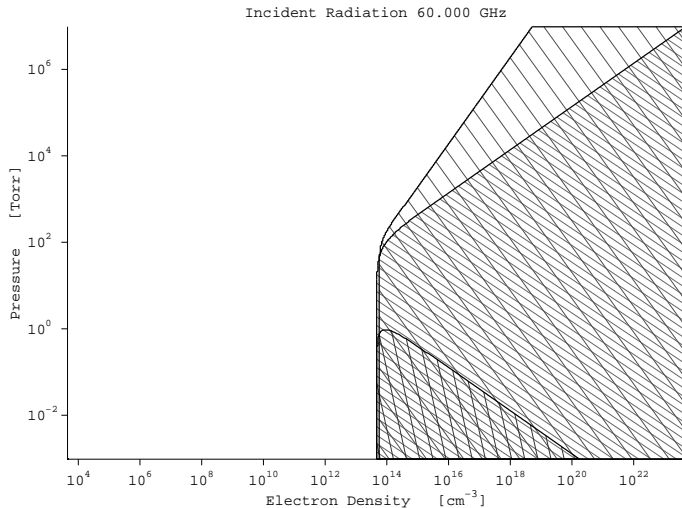
Electron Density and Frequency



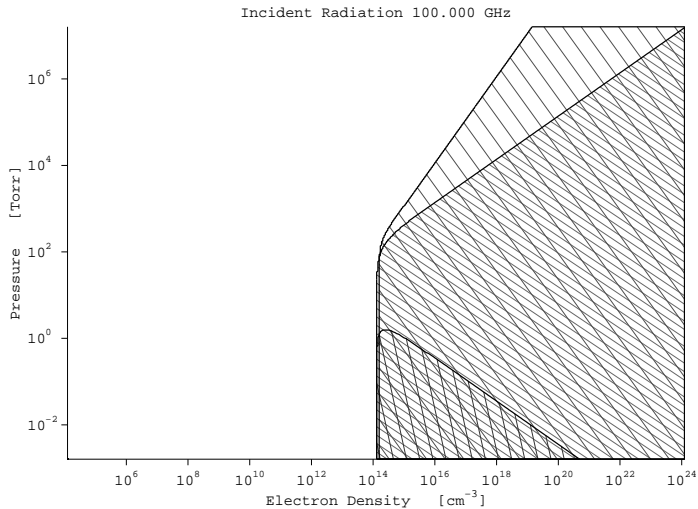
100 MHz Permittivity Map



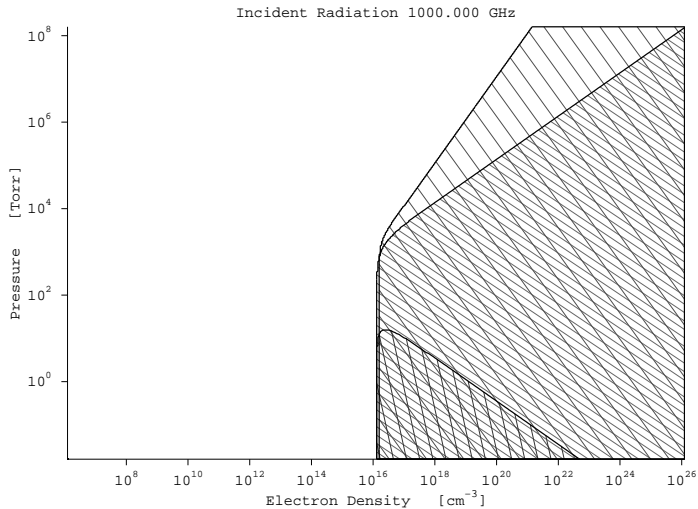
60 GHz Permittivity Map



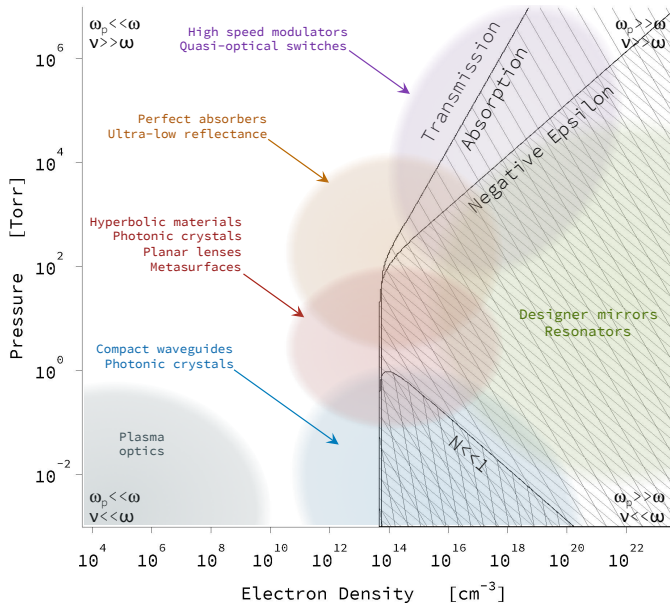
100 GHz Permittivity Map



1 THz Permittivity Map



60 GHz Permittivity Map



1 GHz Permittivity Map

